



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Hou, Chien-Chou; et al.

) Examiner: Deo, Duy Vu N'Guyen

Serial No.: 10/600,377

) Art Unit: 1765

Filed: June 20, 2003

) Our Ref: B-5130 621033-6

For: "METHOD OF ETCHING UNIFORM
SILICON LAYER"

) Date: March 2, 2007

) Re: *Amendment and Response*

AMENDMENT AND RESPONSE

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

This is in reply to the non-final Office Action mailed on December 4, 2006, an initial response to which is due no later than

March 5, 2007.

(Monday)

Please amend the above-identified application as described below and consider the following remarks. **All amendments and remarks herein are made without prejudice.**

Amendments to the Claims are reflected in the listing of claims that begins on page 2 of this paper.

Remarks/Arguments begin on page 6 of this paper.